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DK **'Parallel Kinematic** opens the way to new applications

With its M-840 Hexapod, PI is extending its lead in the field of 6D parallel kinematics technology for ultra-precise applications even further.

Compared with the (high-load) M-850 Hexapod, the M-840 is distinguished by higher speeds and a lower price.

It therefore makes available the numerous advantages of parallel kinematics to a wider range of customers

Did you know that PI has been developing Hexapod MicroPositioning systems for more than one decade? Our piezoelectric NanoPositioning systems were using parallel kinematics as early as the 1980s. You can find out more about parallel kinematics at

http://www.parallemic.org.

6 degrees of freedom

- Minimal moment of inertia for fast response
- High stiffness
- No accumulation of runout errors
- Excellent reproducibility of 2 μm, for multi-axis moves
- True path control
- PivotAnywhere[™] virtualized center of rotation
- User-friendly software and control electronics

Order further information on the M-840.5PD and M-840.5DG (geared version).

Why Hexapods?

A significant advantage of parallel kinematics over stacked multi-axis systems consisting of individual stages is the consistently high precision in all axes of motion:

- No moving cables—friction-free and therefore higher precision and reliability
- No accumulation of the runout of the individual axes-reproducibility of a few micrometers
- No cosine error greater path and positioning precision spatially and about the axes
- No inhomogeneous load distribution-consistent precision about the logical axes

What could your custom Hexapod be able to do? ■ Different scanning ranges ■ Different size ■ Vacuum compatibility (10⁻⁶ hPa)

- Water-resistant
- We will design and build a Hexapod just for you!

The M-840 Hexapod is the newest member of the PI family of parallel kinematic MicroPositioning systems.

Active tools for rapid machining with nanometer precision

How does one achieve effective out-of-round machining on a lathe or produce a facing with a height profile?

Piezo positioning systems make all this possible. Piezo technology is ideally suited to small, high-precision moves. The PZT material exhibits a high degree of intrinsic stiffness, approaching that of aluminum, even in open-loop operation. In closed-loop operation, the stiffness can be set indefinitely high; it can even be negative, if desired. Or extremely low stiffness values can

be set, meaning that the machine actual path of the workpiece which element is virtually allowed to float. In the past, the requirements in the field of precision engineering were expressed in terms of positioning specifications: the system had to reach the required position in milli- or even microseconds. Important was small overshoot, extremely stable position (down to the picometer range) and very low runout (unwanted motion in another dimension).

In today's production technology, by contrast, the high positioning accuracy which can be achieved with piezo systems is of secondary importance.



Active tools, Principle of facing with an active controlled jig.

Here, the dynamic characteristics of the positioning system are much more Piezoelectric tool servo for high-speed out-of-round turning. Travel range +/-125 µm or +/-250 µm. important. Up until

results from the dynamic error of the

positioner). The faster the desired

speed of machining, the more sig-

nificant the tracking error.

PI has carried out pioneering work in this field. Its new digital controllers mean that improvements of a factor of 100 and better can be achieved (see the article on the Digital Linearization Controller, p. 2 for details).

Movement Positioning

Issue 3/2002

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- HEXALIGHT: M-840
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- 2003 preview

Send for further information and speak to us about your applications!

Another worldwide first

PIEZO ACTUATORS WITH CERAMIC INSULATION

The PICMA (PI Ceramic Monolithic Multilayer Actuator) is a new generation of piezoelectric actuators from PI Ceramic which, after many years of research and development, now make available the following advantages over the already outstanding characteristics of our previous actuators:

- Longer lifetime
- Higher dynamic load rating
- Higher operating temperature range
- Higher temperature stability
- Ceramic insulation, no outgassing of polymer insulation materials
- Certified vacuum compatibility
- Extremely well-suited for closed-loop operation







P-885 PICMA actuators

The new actuators are the first and only piezoactuators available worldwide with a 100% ceramic insulation. Conventional piezo actuators are insulated with polymer materials which cannot withstand humidity and other environmental influences as well as ceramics.

Another advantage of PICMA actuators is the extended operating temperature range, up to 150 °C, a huge improvement over the 80 °C limit of other monolithic actuators.

Further information

Request more information about PI Ceramic and the new PICMA actuators.



Comparison between PICMA actuators (blue curve) and conventional multilayer actuators with polymer insulation. Under the test conditions, the PICMA actuators exhibited no reaction to high air humidity while conventional actuators exhibit an increased leakage current after only a few hours. The leakage current is an indicator of the quality of the insulation and of the piezoceramic's lifetime. Test conditions U = 100 V_{DC}, T = 25 °C, rel. humidity = 70 %

Application areas for PICMA

- NanoPositioning
- High-speed switches
- Scanning microscopy
- Active optics
- Micropumps
- Microdosage
- Laser tuning
- Biotechnology
- High-speed valves
- Metrology, interferometry

PI Ceramic

Founded 10 years ago, PI Ceramic is a subsidiary of the world's leading supplier of NanoPositioning systems, Physik Instrumente (PI) in Karlsruhe, Germany.

PI Ceramic specializes in the design and production of PZT components, piezoelectric actuators (high-voltage and low-voltage designs), ultrasonic sensors and customized solutions.

100 % vacuum compatible: The DLR (German Space Agency) certifies "no measurable outgassing" rates for PICMA (according to the Micro-VCM/ ESA-PSS-01-702/ATM595 and EC95Q-70-02A standards).





The solution for scanning applications

Improve dynamic positioning accuracy by up to 1000 times

Piezo-driven NanoPositioning systems achieve higher resolutions and positioning accuracies than any other positioning systems. And the sub-nanometer region does not represent the limit.

Today there are more and more applications, however, in which high accuracy alone is not sufficient; dynamic accuracy in the nanometer region is what is required. Until now, the limiting factor has been the control technology.

In order to increase throughput, many scanning applications no longer waste time stopping at the commanded position to record measurement data. Wherever possible, recording is done "on the fly" with the stage in motion.

This means that the NanoPositioning system is only permitted an extremely small tracking error (deviation of the actual from the commanded path), something not possible with conventional P-I-D controllers.

Scanning to the nanometer: **Dynamic Digital Linearization**

With the new E-710 upgrade option "Dynamic Digital Linearization" tracking errors are reduced by a factor of 100 to

1000-to the order of magnitude of a few nanometers

This new controller operates with all periodic signals (even complex composite scan functions involving several axes). In several "test

runs" the controller analyzes the dynamic error and automatically adjusts the parameters so that the tracking error is reduced to a few nanometers. This process typically takes less than a second.



Effect of Digital Linearization on the dynamic positioning accuracy of a Nano-Scan system. The tracking error, shown magnified by 100, was reduced by a factor of 900 compare with conventional a P-I-D controller



device With its im-

proved design,

the ultra-high-pre-position feedback. cision capacitive

feedback version of the P-721 PIFOC objective nanopositioner and scanner family can now be equipped with M25 objectives for inverted microscopes. In addition a large variety of other objective thread types and sizes can now also be selected when ordering.

Highlights:

- (Automated) microscope objective adjustment and scan with resolutions <1 nm
- Capacitive feedback for highest linearity and position stability
- Travel to 100 µm
- Fast step-and-settle

Stable positioning of objectives to within a nanometer!

New PI Website provides more information: www.pi.ws

At PI, we recently completely re-designed our Internet presence. At www.pi.ws you can find information on our products, our newsletter, job vacancies as well as our compre-

hensive tutorials. We hope you will visit our website soon. We welcome your suggestions and comments.





et site navigation is simple and intuitive.

PIHera Nano-Translation Stages

< 1 nm resolution 0.5 mm travel range

Nanopositioning over 0.5 mm:

P-620 PIHera stages are piezo NanoPositioning systems which combine long travel ranges of up to 500 μ m with high-precision motion in the smallest possible package. The large travel ranges are achieved by means of a new type of frictionfree, and extremely stiff, lever system which allows high precision and fast step-and-settle.

- Travel ranges up to 500 µm
- Compact dimensions
- < 1 nm resolution</p>
- New piezo drives with increased lifetime
- Capacitive position feedback system for highest possible linearity and repeatability (closedloop versions)
- 0.01 % positioning accuracy
- Typ. < 5 µrad travel precision
- Low cost
- Vacuum versions available

Order PIHera:

PIHera is available in three versions with or without sensor:

- P-621.1CD / P-621.10L
 100 µm travel, dimensions:
 40 x 40 x 15 mm³
- P-622.1CD / P-621.10L
 250 μm travel, dimensions:
 50 x 50 x 15 mm³
- P-625.1CD / P-625.10L
 500 µm travel, dimensions:
 60 x 60 x 15 mm³

PIHera stages are equipped with PICMA actuators! (See related article p. 1)



Low-cost solution: PIHera with the new E-665 Controller

Design your own system:

The PIHera operating principle allows flexible designs for customized solutions—from the dimensions and scanning ranges through integrated XY systems to their vacuum compatibility. Ask for further information about the PIHera (P-620) series stages.

Step-and-settle times and scanning with PIHera

In order to squeeze a 500 µm scanning range out of a piezodriven stage with such compact dimensions, an ingenious lever system is required. PIHera possesses an unrivalled high mechanical stiffness and a correspondingly high resonant frequency for fast step-and-settle times. Optimized for scanning operations, PIHera can be used with the latest digital controllers. For more information, read the article on linearization (p. 2) and ask us for additional material.

IntelliStep[™]

A step toward greater flexibility in automation technology

> Motor, controller and amplifier in one package, networkable with up to 9 units.

IntelliStep drives: Modular and lowcost automation. Stepper motor and controller in one!

Advantages:

Reliability: no cable between controller and drive, fewer components, motion unit reduced to one assembly!

Compactness: controller integrated

Network functionality: up to nine IntelliStep motors can be chained together!

Simplicity: the whole network is controlled over one RS-232 interface!

Modularity: manual stages can be retro-fitted!



Compatibility: fully compatible with PI's IntelliStage[™] and Apollo stepper motor controller systems, and with PI's micropositioning stages!

Pl precision: 20,000 micro-increments /revolution for high resolution and smooth motion! P-625, P-622, P-621 front to back

More PI News: Click here: http://www.pi.ws/e_news

AVAILABLE SOON



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JANUARY 20 to 23 · NanoTech · Kyoto · Japan 22 to 24 · FiberOptics · Tokyo · Japan 25 to 26 · Biomedical Optics San Jose, CA · USA 28 to 30 · Photonics West San José, CA · USA

FEBRUARY

3 to 6 · IMAC · Kissimmee, FL · USA 4 to 6 · Teknik & Data · Odense · Denmark 12 to 13 · IPOT · Birmingham · England

MARCH

4 to 5 · Smart Structures San Diego, CA · USA 25 to 27 · OFC · Atlanta, GA · USA 25 to 27 · ELKOM · Helsinki · Finland 25 to 28 · Intertronic · Paris · France 27 to 30 · Applied Physics Society, Kanagawa University · Kanagawa · Japan

APRIL

1 to 3 · Electronica · Tel Aviv · Israel 1 to 3 · Solutions Visions · Paris · France 1 to 3 · Semicon Europe Munich · Germany 7 to 12 · Hannover Fair Hannover · Germany 16 to 18 · Motor Technology Makuhari · Japan

MAY

6 to 8 · Noise & Vibration Traverse City, MI · USA 6 to 9 · Control · Sinsheim · Germany 6 to 10 · Semicon (SICEC) Singapore · Singapore

JUNE

2 to 4 · SEM Annual Conference Charlotte, NC · USA 3 to 5 · CLEO · Baltimore, MD · USA 23 to 25 · Noise-Con Cleveland, Ohio · USA 23 to 26 · LASER 2003 Munich · Germany 23 to 27 · INFM Meeting · Rome · Italy

JULY

14 to 16 · Reunion Nacional de Optoelectronica (Optoel) Madrid · Spain 14 to 16 · Semicon West San Francisco, CA · USA 13 to 18 · ICOLS 03 · Palm Cove · Australia

AUGUST

27 to 29 · AEL · Helsinki · Finland

SEPTEMBER

2 to 5 · Komponent/Elektronikproduktion Göteborg · Sweden 9 to 11 · Automaatio · Helsinki · Finland 21 to 25 · ECOC · Rimini · Italy

OCTOBER

8 to 9 · Photonex Stoneleigh, Coventry · England 7 to 11 · Tekniska Mässan Stockholm · Sweden 22 to 24 · Opto-Physique · Paris · France 28 to 30 · Electro Optics · Tel Aviv · Israel

NOVEMBER

11 to 14 · Productronica Munich · Germany 26 to 27 · Mocon Den Bosch · Netherlands 19 to 21 · Micromachine · Tokyo · Japan

DECEMBER 3 to 5 · Semicon · Tokyo · Japan

NanoPositioning controller for 1 to 12 axes

The E-665 is a new low-cost single-channel controller for piezo NanoPositioning systems equipped with high-resolution capacitive sensors. The controller features both an analog input mode and a fast digital interface which allows up to 12 devices to be networked.



- Integrated 20-bit D/A converter and high-speed RS-232 interface
- Network capability with up to 12 channels
- 36 W peak power
- For strain gauge, LVDT or capacitive sensors

The E-665.CR version (for capacitive sensors) combines with the new PIHera Nano-translation stages or PIFOC Nano-Focus-Systems to provide a low-cost, high-performance system.

The M-110 Family Compact highresolution micropositioning stages

The M-110 are compact motorized translation stages which over the years have grown into a complete family of products with a successful market position.

Product-Highlights

- Travel ranges 5, 15 and 25 mm
- Minimum incremental motion 50 nm
- Velocity to 2 mm/s
- Integrated limit and position reference switches
- XY/XYZ mountable
 Hybrid versions with
- NanoCube™ e.g. for fast fiber alignment tasks

Version overview:

	Travel range	Motor	Drive
M-110.1DG	5 mm	DC	Leadscrew
M-110.2DG	5 mm	DC	Recirculating ballscrew
M-110.12S	5 mm	Stepper	Leadscrew
M-110.22S	5 mm	Stepper	Recirculating ballscrew
M-111.1DG	15 mm	DC	Leadscrew
M-111.2DG	15 mm	DC	Recirculating ballscrew
M-111.12S	15 mm	Stepper	Leadscrew
M-111.22S	15 mm	Stepper	Recirculating ballscrew
M-112.1DG	25 mm	DC	Leadscrew
M-112.2DG	25 mm	DC	Recirculating ballscrew
M-112.12S	25 mm	Stepper	Leadscrew
M-112.22S	25 mm	Stepper	Recirculating ballscrew

M-110 XYZ-hybrid system with NanoCube[™] for extremely fast positioning in the nanometer range.

More PI News: Click here: http://www.pi.ws/e_news

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NEWS BRIEF!

Ultra-long range

Scanning or beam-steering about 2 axes in milliseconds, up to ± 1.5°, with sub-µrad resolution

World record for a piezo scanner: ± 25 mrad

S-334 tilt mirrors are fast and compact units providing highly precise angular motion in two orthogonal axes. The tip/ tilt range can be up to ± 25 mrad with a resolution in the sub-µrad range. In closed-loop operation, the S-334 offers outstanding positioning ac-

curacy and stability.

Highlights

- Tip/tilt range up to ± 25 mrad (± 1.5 °) in 2 fixed orthogonal axes
- 1 kHz resonant frequency with mirror
- For mirrors up to 12.5 mm (0.5") diameter
- Angular resolution in the sub-µrad range

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Coming Soon Movement & Position 1/2003

In the next edition of M&P, which is scheduled to appear in Spring 2003, we will present our new, small, power-packed positioning stages.

Attention, AFM users: Do you need a stage no larger than $30 \times 30 \times 30$ mm³ (1.2 in), with > 7 µm travel, resolution of <0.1 nm along all three axes and equipped with capacitive feedback sensors? PI has it: speak with us today.

PI*line*, the drive which moves you, is available as an **OEM drive**. **PI***line* refers to our line of piezo linear motors providing unlimited travel with submicrometer resolution in a compact package.

In addition, you will be given a preview of the **LASER 2003** in Munich (23-26 June 2003).

C-843 Motion Controller Card Features On-board linear amplifiers & PWM outputs

The new C-843 motion controller card from PI directly drives up to 4 axes of micropositioning equipment without the need for external amplifiers.

Unlike other PCI controller cards, the

new C-843 comes with onboard linear amplifiers for the small DC

motors used in most compact micropositioning stages and actuators. In addition,

PWM outputs are available to drive more powerful equipment (all direct-drive translation and rotation stages from PI feature the integrated ActiveDrive™ PWM amplifiers, and hook up to the C-843 with no external power amplifiers).

For ease of operation, the C-843 is compatible with the PI General Command Set and comes with a comprehensive software package including LabView[™] drivers.

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New PI Website provides more information:

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